



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No.	10/072,357	Confirmation No.	4288
First Inventor	Michael D. Kilgore	Filing Date	2/6/2002
Tech. Center/ Art Unit	2822	Examiner	Maria F. Guerrero
Title:	High Density Plasma Process For Optimum Film Quality And Electrical Results		
Docket No.:	NVS014 US	Customer No.:	34036

Santa Clara, California
September 19, 2005

Mail Stop AF
COMMISSIONER FOR PATENTS
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL ACTION

Dear Sir:

In response to the Office Action dated May 18, 2005, please amend the above-identified application as follows.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.